

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: KATO, et al.  
Filed: January 22, 2001  
For: VACUUM PROCESSING APPARATUS AND OPERATING  
METHOD THEREFOR



J. Henson

# 3  
7/26/2001

**INFORMATION DISCLOSURE STATEMENT**  
**UNDER 37 CFR 1.97 AND 1.98**

Assistant Commissioner for Patents  
Washington, D.C. 20231

January 22, 2001

Sir:

Pursuant to Applicants' duty of disclosure, enclosed please find a List of documents cited in connection with prior applications of the above-identified application. The listed documents were cited in at least one of the following U.S. patent applications, for which benefit has been claimed under 35 USC 120 in the above-identified application:

- (1) Application Serial No. 09/461,432,  
filed December 16, 1999;
- (2) Application Serial No. 09/177,495,  
filed October 23, 1998;
- (3) Application Serial No. 09/061,062,  
filed April 16, 1998;
- (4) Application Serial No. 07/751,951,  
filed August 29, 1991, now U.S.  
Patent No. 5,314,509, issued May 24,  
1994;
- (5) Application Serial No. 08/096,256,  
filed July 26, 1993, now U.S. Patent  
No. 5,349,762, issued September 27,  
1994;
- (6) Application Serial No. 08/443,039,  
filed May 17, 1995, now U.S. Patent  
No. 5,553,396, issued September 10,

1996;

- (7) Application Serial No. 08/593,870,  
filed January 30, 1996, now U.S.  
Patent No. 5,661,913, issued  
September 2, 1997; and
- (8) Application Serial No. 08/882,731,  
filed June 26, 1997.



In particular, note that each of these listed documents cited in connection with prior applications, was cited in application Serial No. 09/461,432, filed December 16, 1999.

The listed documents have been cited in connection with at least one prior application of the above-identified application for which priority has been claimed under 35 USC 120; accordingly, copies of the listed documents are not enclosed.

Of the listed documents, attention is particularly directed to U.S. Patent No. 4,923,584 and Japanese Patent Document No. 63-153270. Please note that a partial English translation of Japanese Patent Document No. 63-153270 has been submitted in connection with prior applications of the above-identified application, for which priority has been claimed under 35 USC 120. In addition, enclosed is a full English translation of Japanese Patent Document No. 63-153270. Also enclosed is a copy of U.S. Patent No. 4,923,584.

In addition, note the following comments concerning various of the listed documents which are not in English. JP No. 2-61064 corresponds to U.S. Patent No. 4,969,790 (also listed), and relates to a merry-go-round system. JP No. 1-310553 relates to a single chamber. JP No. 1-251734 relates

to a vacuum cassette. JP No. 62-44571 relates to an ion implantor. JP No. 62-50463 relates to a sputtering device; and JP No. 2-106037 relates to a single chamber device. JP No. 57-29577 relates to a sputtering device. In "Semiconductor Equipment Association of Japan", a load lock chamber is defined.

This Information Disclosure Statement is being submitted concurrently with the filing of the above-identified application. Accordingly, it is respectfully submitted that requirements of 37 CFR 1.97(b) are satisfied.

To the extent that the enclosed documents are not in English, it is respectfully submitted that the requirements of 37 CFR 1.98(a)(3) are satisfied by the previously submitted abstracts of various of the documents not in English, partial English translation of various of the documents not in English, the foregoing comments, and the presently submitted full English translation of JP No. 63-153270.

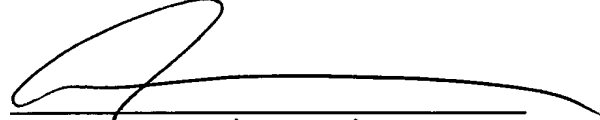
In view of all of the foregoing, it is respectfully submitted that all requirements of 37 CFR 1.97 and 1.98 have been satisfied, in connection with the documents on the enclosed List. Accordingly, consideration of the listed documents, upon examination of the above-identified application, are respectfully requested.

To the extent necessary, Applicants petition for an extension of time under 37 CFR § 1.136. Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to the Deposit

Account No. 01-2135 (Case No. 503.30414V20) and please credit  
any excess fees to such Deposit Account.

Respectfully submitted,

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AES/slk  
Enclosures